



Docket No.: H0498.70130US01
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tao Deng et al.
Serial No.: 10/763,819
Confirmation No.: 5026
Filed: January 23, 2004
For: FABRICATION OF METALLIC MICROSTRUCTURES VIA
EXPOSURE OF PHOTSENSITIVE COMPOSITION
Examiner: K. Duda
Art Unit: 1795

Certificate of Mailing Under 37 CFR 1.8(a)
I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as First Class Mail, in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Dated: 1/30/08

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated December 12, 2007, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.